

The Philips logo is displayed in a white rounded rectangle in the top-left corner of the image. The word "PHILIPS" is written in a bold, blue, sans-serif font.

PHILIPS

The background of the slide is a photograph of a large, modern Philips building with a grid of windows and a prominent tree in the foreground. The sky is clear and blue.

Exciting and new;  
based on existing and proven

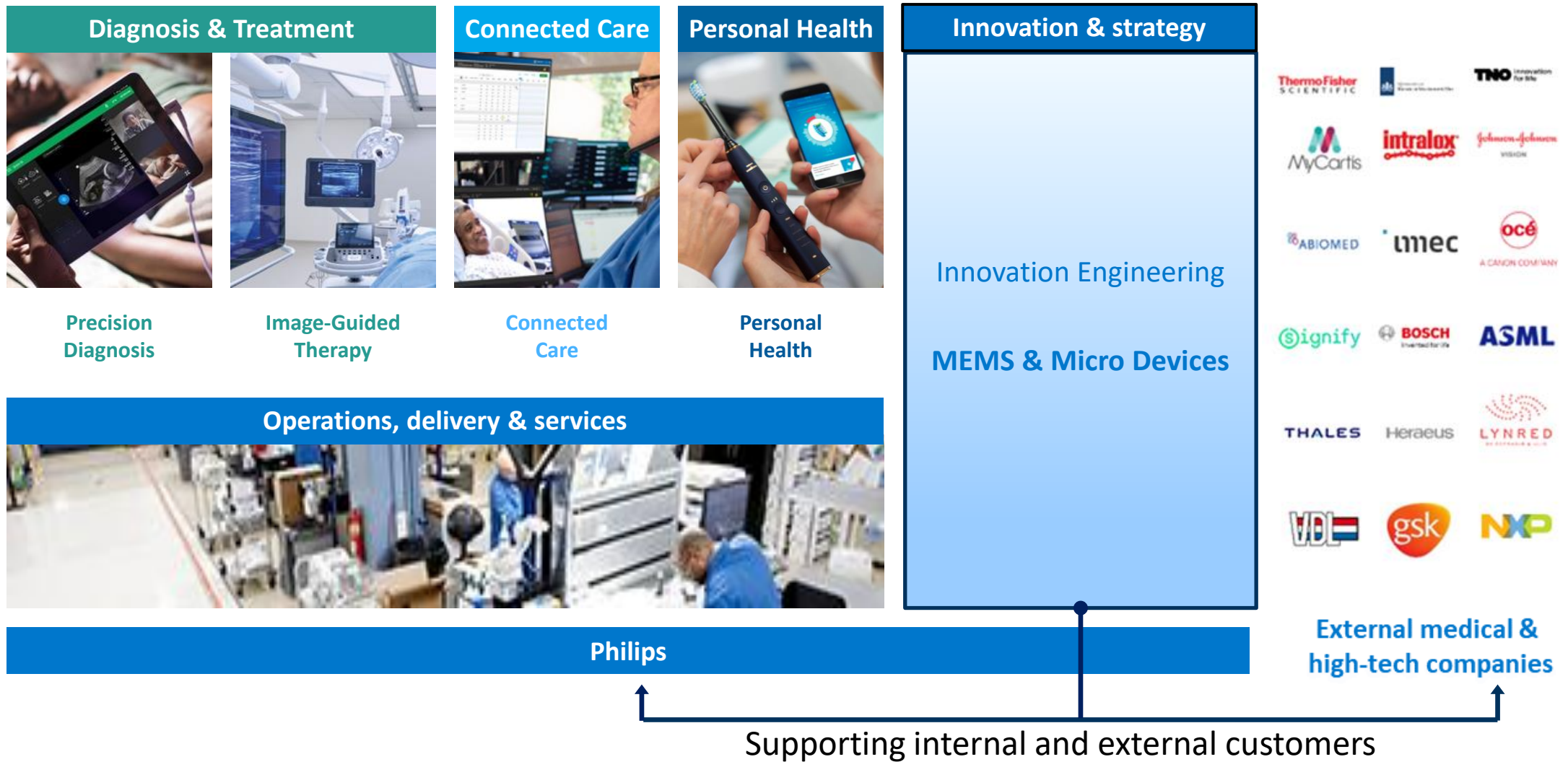
Paul Dijkstra  
Philips Micro Devices  
June 15, 2023

innovation ✨ you

# Content

- Introduction MEMS & Micro Devices
- Development philosophy
- Conventional semiconductor processes
- Module interfaces and its challenges
- Miniaturisation conventional technology
- New 3D miniaturisation platform: F2R
- 3D miniaturisation examples
- New Interfaces
  - Optical
  - Acoustic
  - $\mu$ -fluidic
- Conclusions

# MEMS & Micro Devices - in Innovation Engineering



# MEMS & Micro Devices

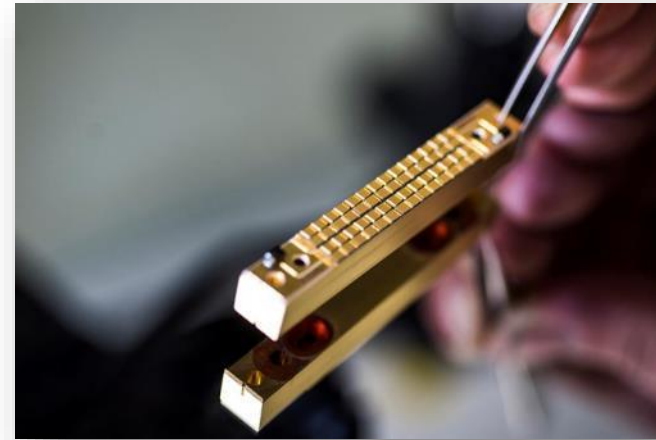
## *Process Development and Manufacturing*



MEMS & thin film products



Micro (Device) assembly & complex PCBA



2650 m<sup>2</sup>  
Cleanroom  
FTE: ~100



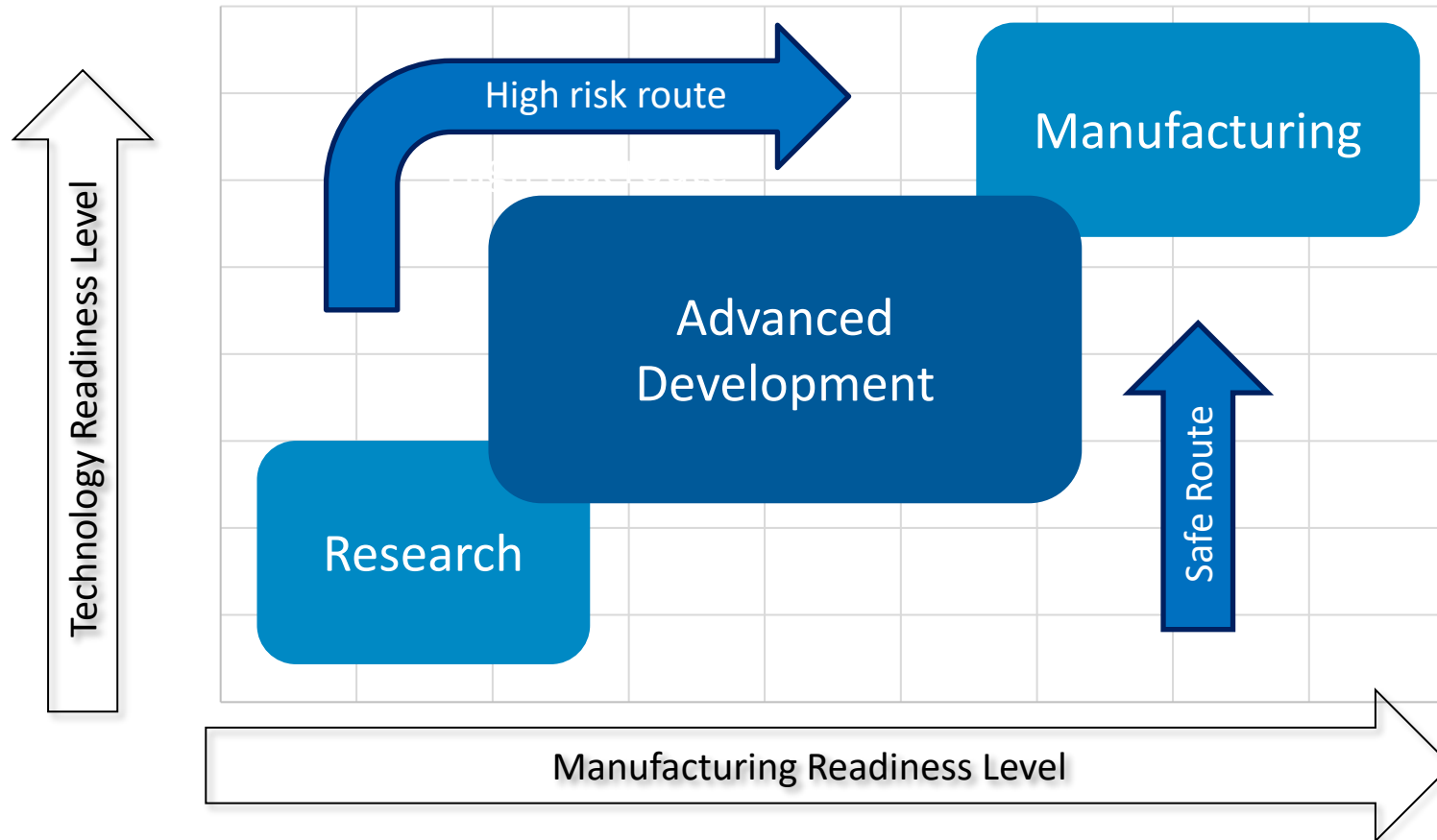
High Tech Campus, Eindhoven

2500 m<sup>2</sup>  
Factory +  
Cleanroom  
FTE: ~70



"Greenhouse" Strijp-S, Eindhoven

# Development philosophy



## Advanced development

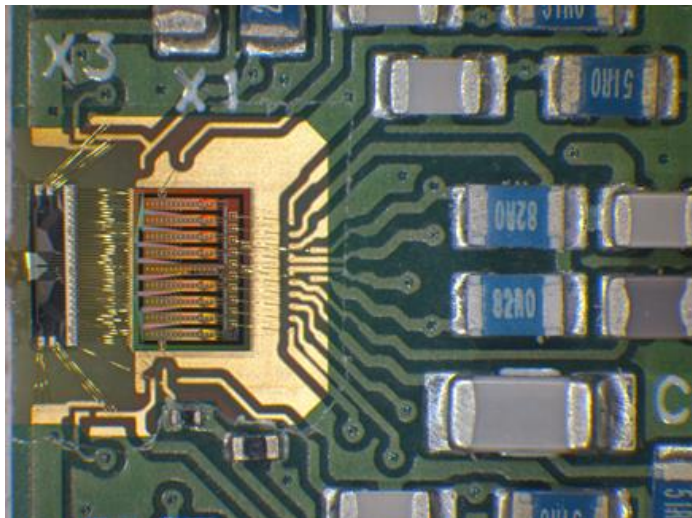
- Focus on de-risking / quick learning
- Select concept & technologies
- All functions to be incorporated into the Architecture are proven
- **Process windows and Transfer functions** for CTQ's known

Doing the exciting and new based on the existing and proven

# Existing and proven semiconductor assembly processes

## Conventional technologies

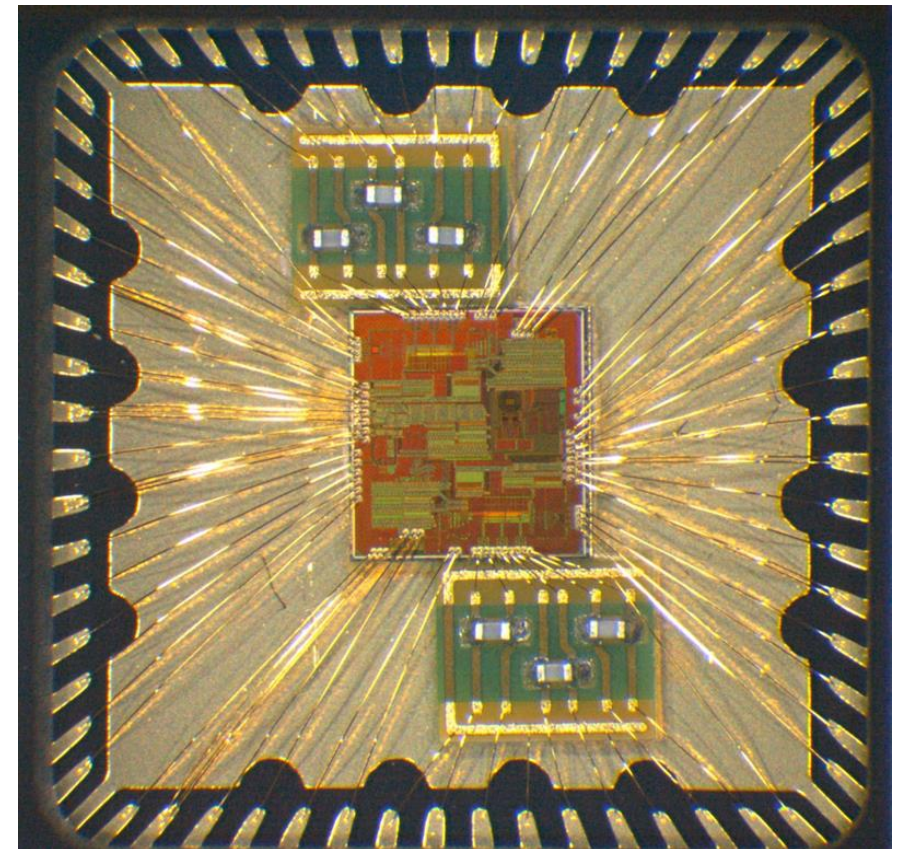
- Die bonding with adhesive or solder
- Flipchip soldering
- Au and Al wirebonding
- ACF bonding of die to carrier (flex)
- Encapsulation: moulding or globtop
- PCB assembly



CMUT benchboard

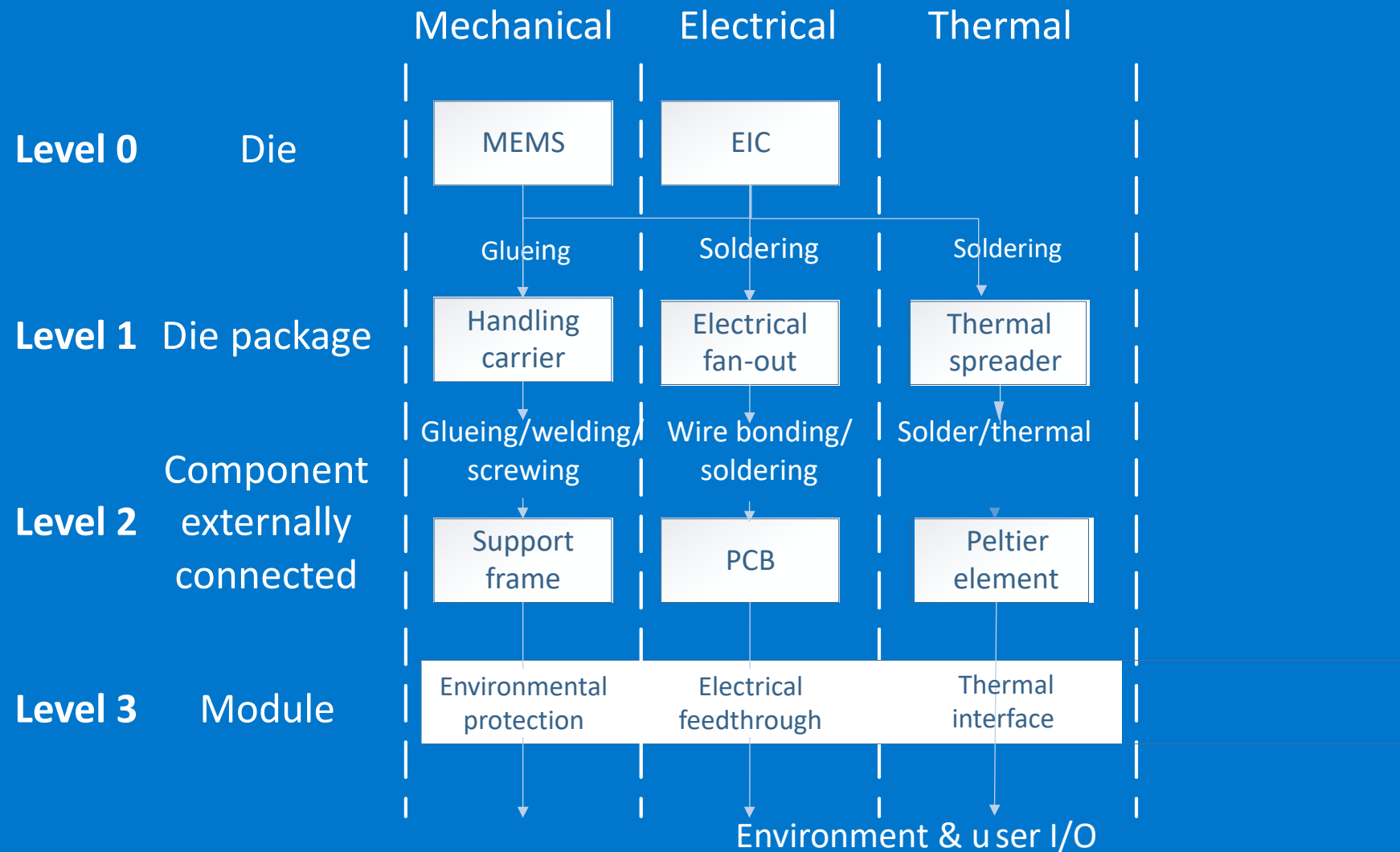


Encapsulated Au wires

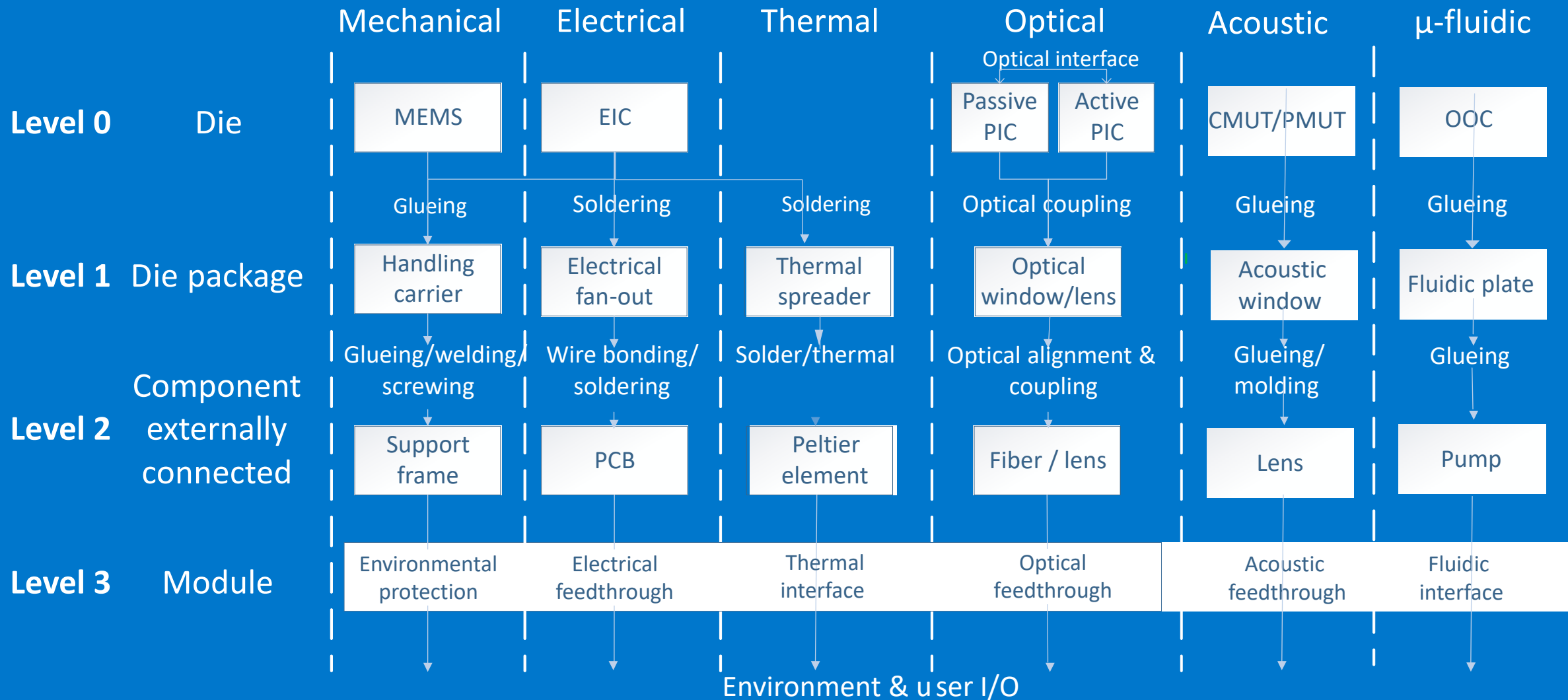


ASIC with added capacitors

# Known and proven interfaces semiconductor



# New extended interfaces





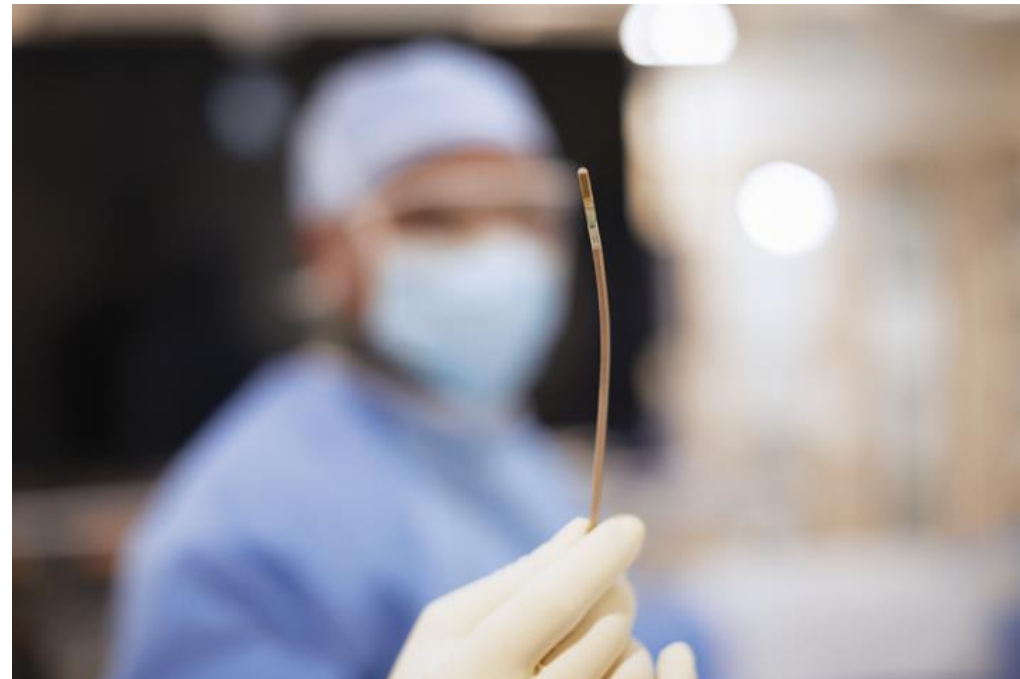
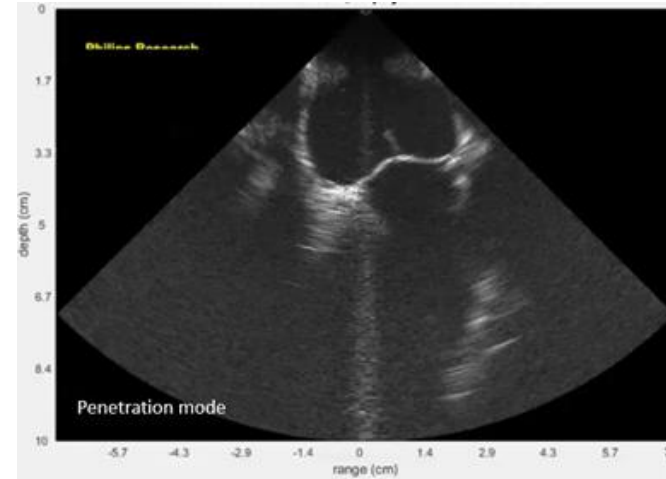
# Interface challenges for new application area's

Interface	Challenges
Thermal/Mechanical/electrical	Miniaturisation, 2D->3D, new interfaces
Acoustic	Material stack, interface and shape
Optical	Relative position accuracy and stability
$\mu$ -fluidic	Leaktight, environmental conditions

# Miniaturisation conventional technology

## *Imaging core ICE*

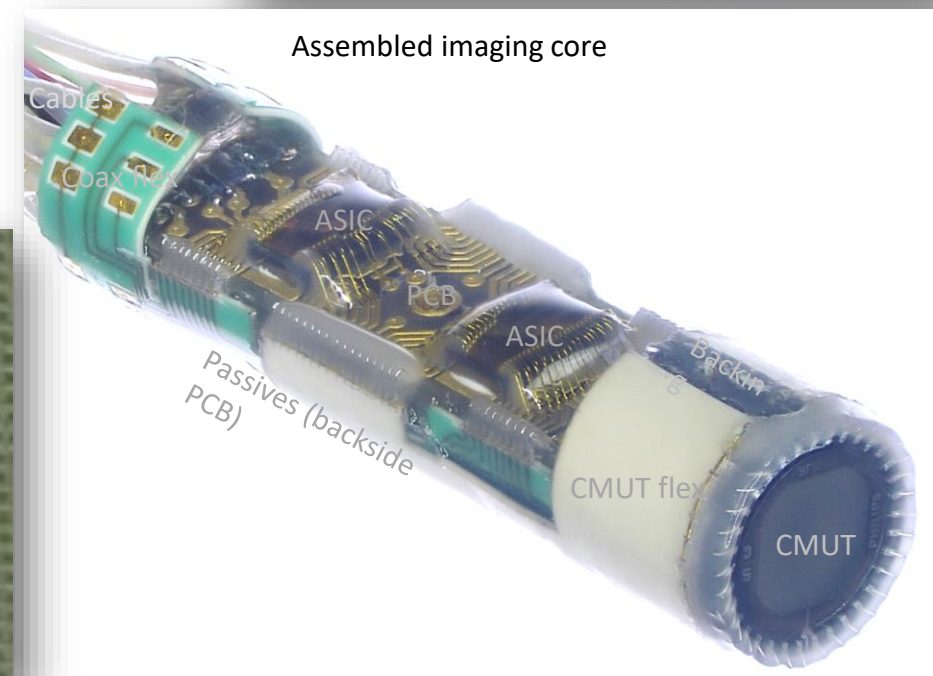
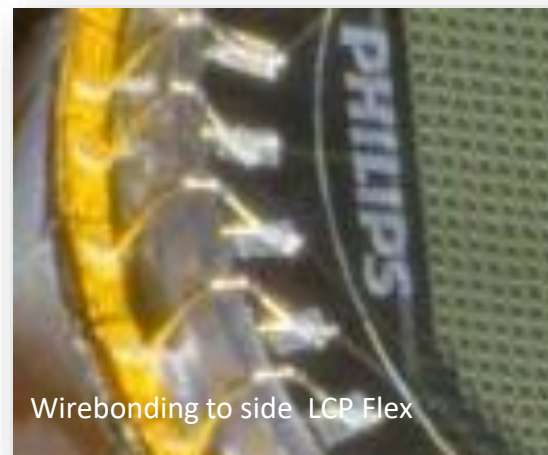
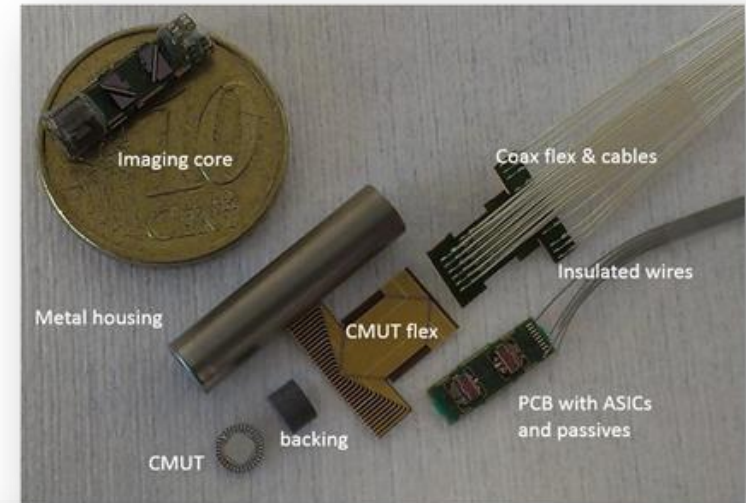
- Acoustic ultrasound sensor
  - Single crystal technology
  - Side looking
  - 2D and 3D images
  - $\varnothing$  3 mm (9 Fr)
- Assembly challenges
  - Connecting cable assy to acoustic assy
  - Handling odd form factor (2.8 m cable)
- Proven assembly technologies
  - Component placement
  - Au wirebonding
  - Globtop



# Miniaturisation conventional technology

## *Imaging core FL-ICE*

- Acoustic ultrasound sensor
  - CMUT technology
  - Forward looking
  - 2D images
  - $\varnothing$  4 mm (12 Fr)
- Assembly challenges
  - Miniaturisation
  - 3D form factor based on conventional LCP flex
  - Wirebonding on side edge of flex
- Proven assembly technologies
  - PCB assembly
    - ASIC/PCB
  - Al wirebonding
    - CMUT/flex

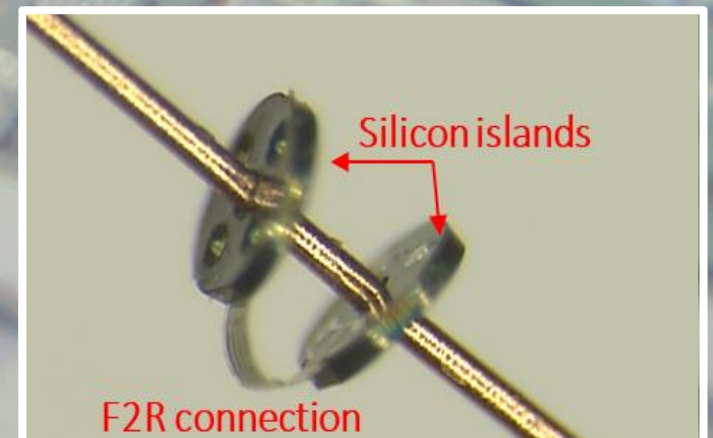
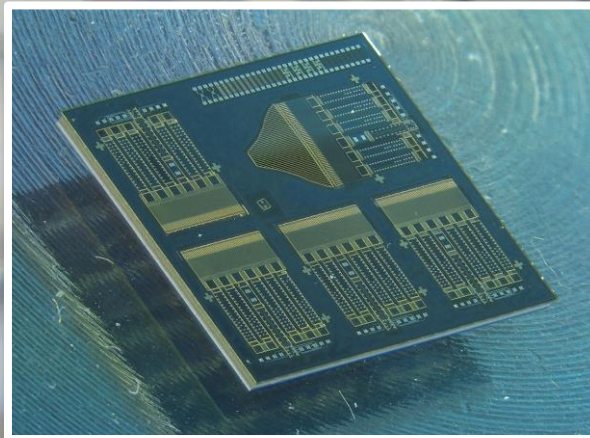
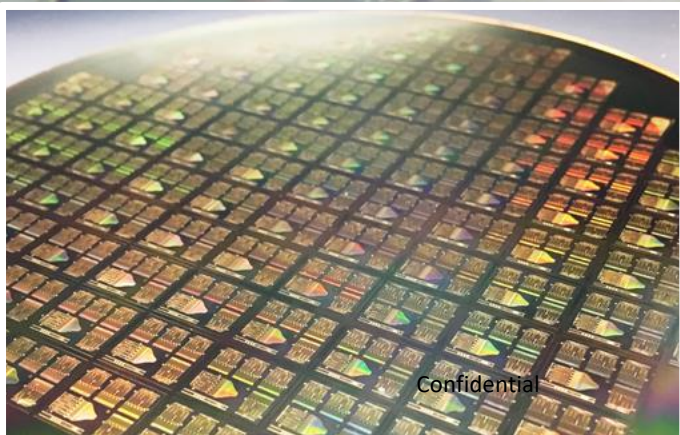


# New 3D miniaturisation platform: F2R



## Flex-to-Rigid (F2R) silicon carrier

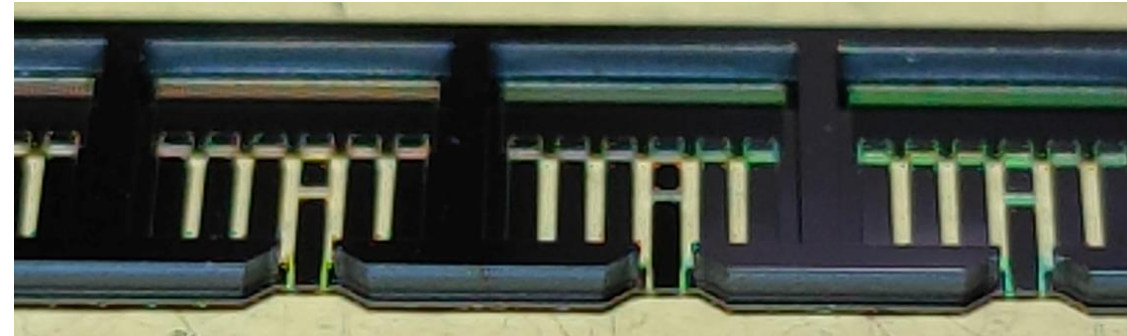
- Wafer level processing with integrated interconnects
- Seamless sensor integration
- 2D assembly and folding into 3D configuration
- Compatible with proven technologies



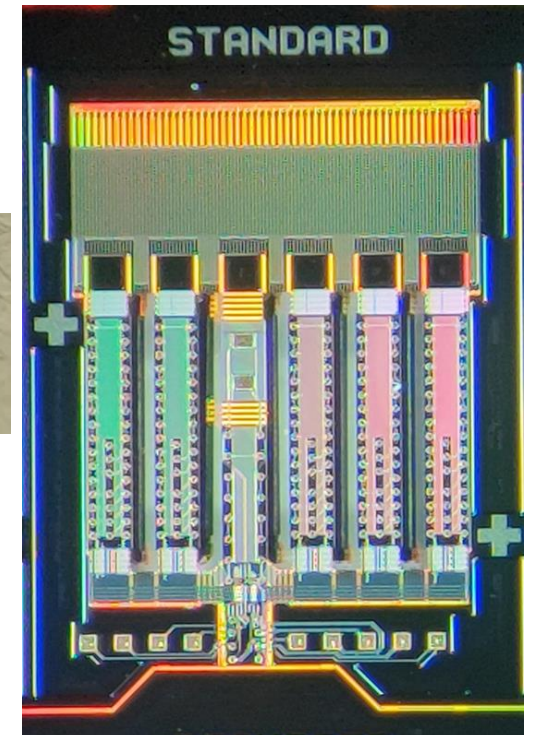
# New 3D miniaturisation platform: F2R

## *Key characteristics*

- Starting material SOI wafer
  - Device layer 40  $\mu\text{m}$ , handle 380  $\mu\text{m}$
- Tracks embedded in two layers of PI bridging Si islands
  - Enables folding due to flexibility
- Wafer divided into frames for handling and processing

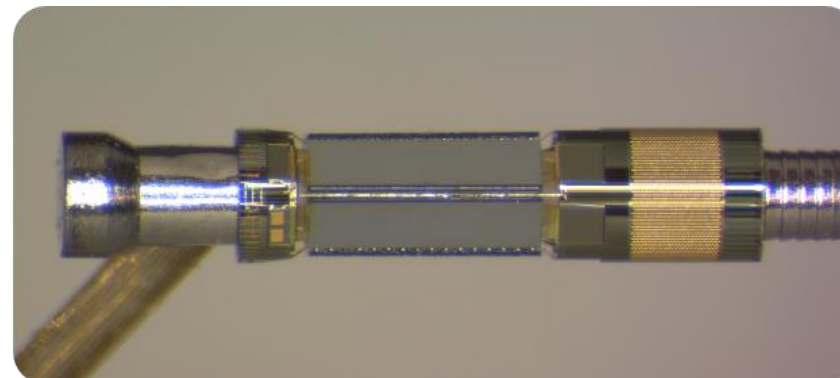
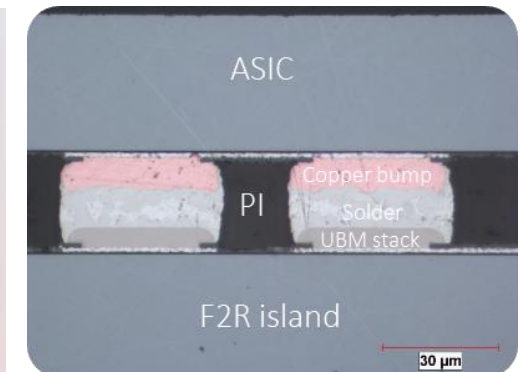
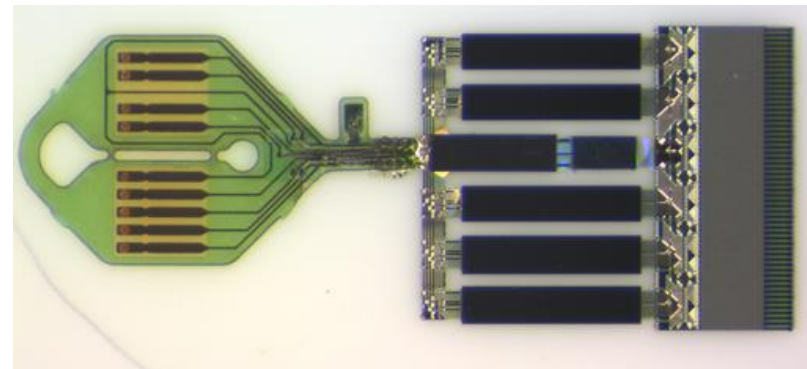
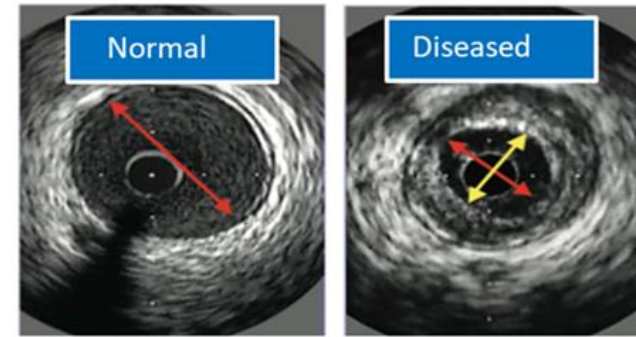


Frames used in processing



# New 3D miniaturisation platform: F2R *IVUS imaging core*

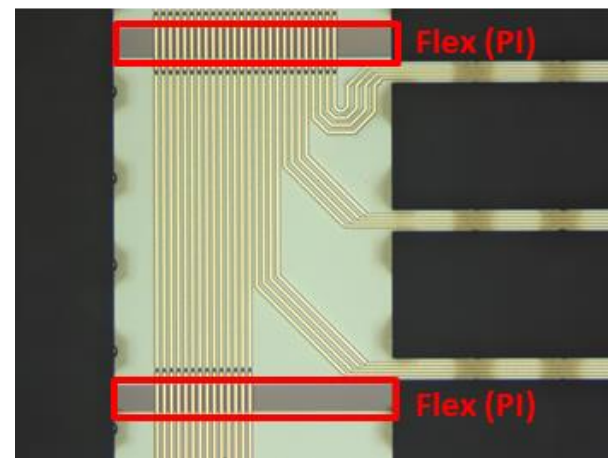
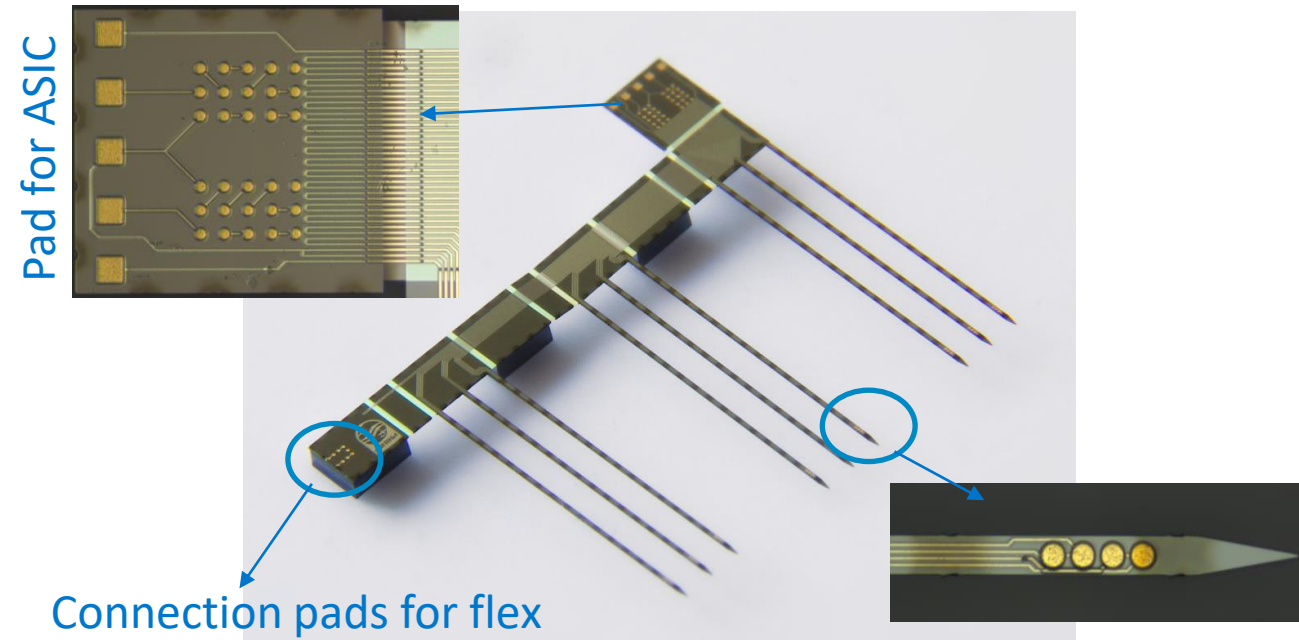
- Acoustic ultrasound sensor
  - CMUT technology: 114 element lines
  - 6 ASIC's and 1 capacitor
  - 360 degree image
  - 2D plane view
  - $\varnothing$  1 mm (3 Fr)
- Assembly challenges
  - Miniaturisation
  - Assembly processes on 40  $\mu$ m thick Si islands
  - 3D form factor
- Proven assembly technologies
  - Flip chip die bonding
  - ACF flex attach
  - Underfill
- New assembly technologies
  - 3D shaping and fixation with adhesive



# New 3D miniaturisation platform: F2R

## Bio-MEMS

- $\mu$ -needle array
  - Sensing electrodes
  - Array of 5 mm long needles,  $72\mu\text{m}$  wide \*  $40\mu\text{m}$  thick
  - Array can be formed by folding or rolling
  - Integration of ASIC's for data processing
  - Flex to interface with external electronics
- Assembly challenges
  - 2D assembly and 3D geometry
  - Handling small delicate parts
- Proven assembly technologies
  - ASIC flipchip bonding
  - ACF flex bonding
- New assembly technologies
  - F2R folding and fixation with adhesive

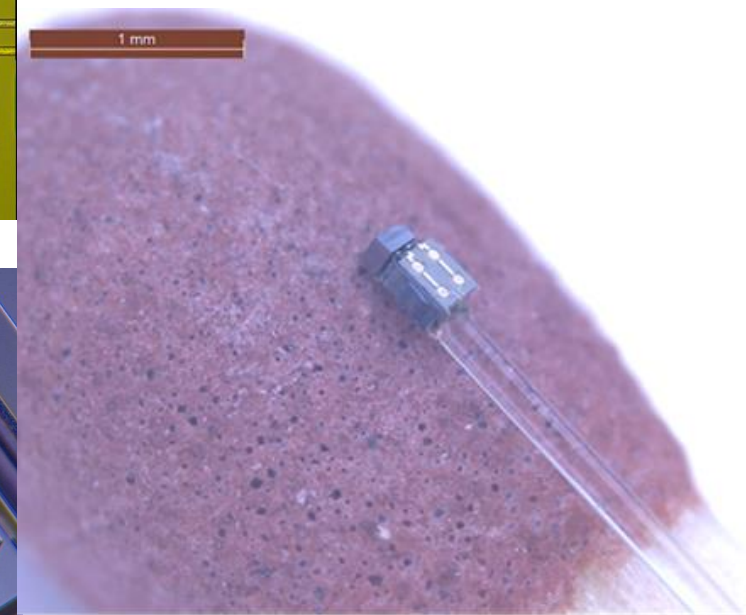
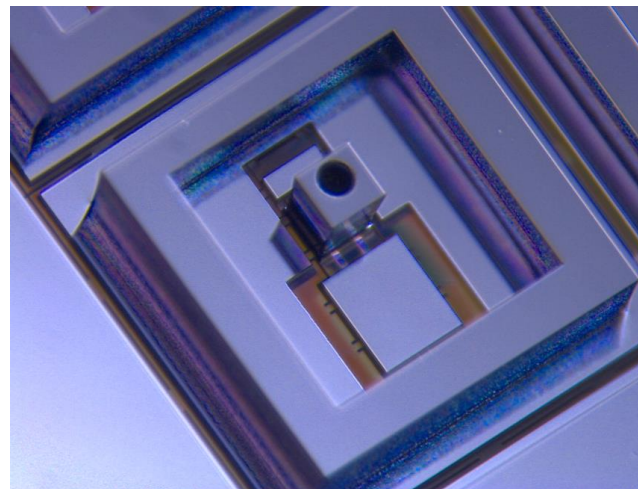
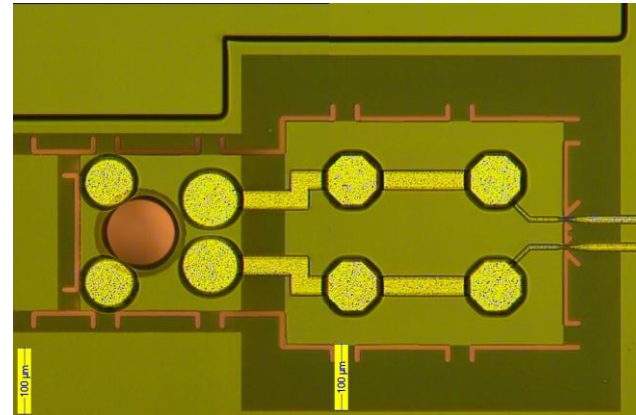


Folded  $\mu$ -needle array

# New 3D miniaturisation platform: F2R

## Photonic

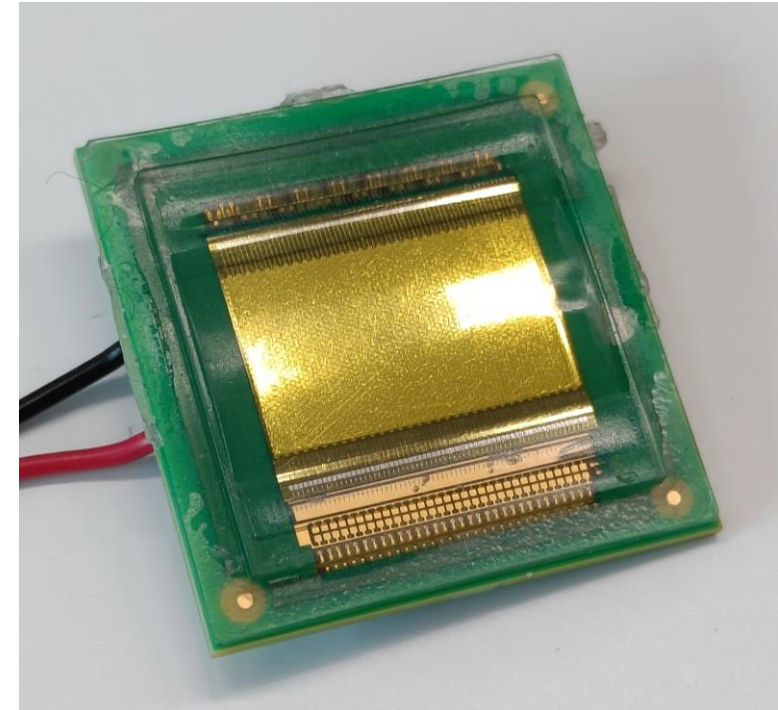
- Optical link module
  - Power transfer or data transfer
  - Dimensions enable integration in catheters
  - Footprint enables flipchip soldering to other carrier
- Assembly challenges
  - Miniaturisation and 3D geometry
- Proven assembly technologies
  - VCSEL flipchip bonding
  - Optical fiber insertion and fixation with adhesive
- New assembly technologies
  - F2R folding and fixation with adhesive





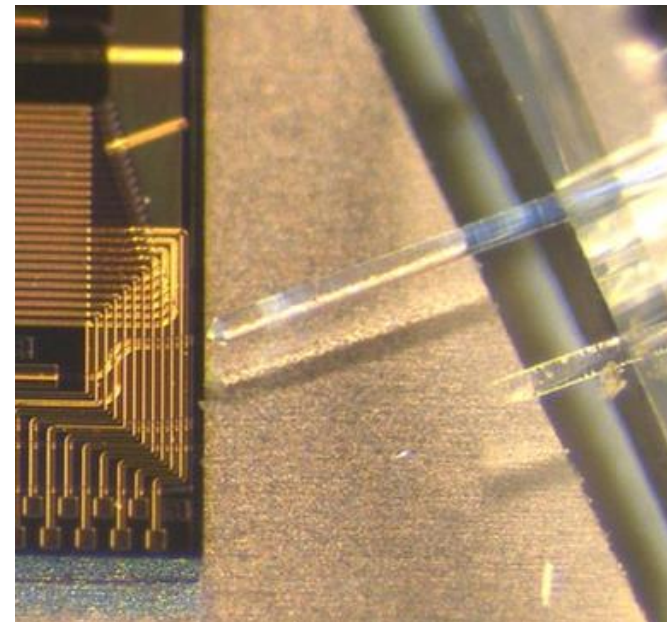
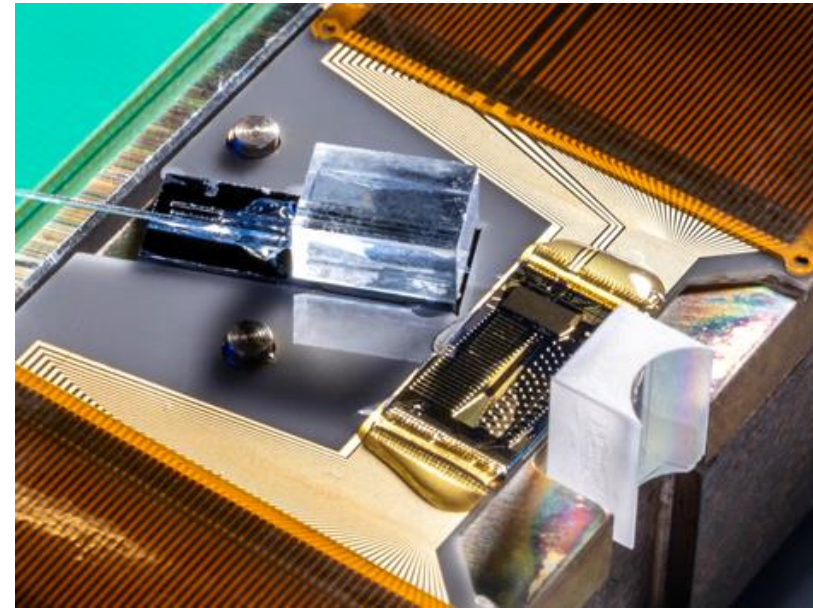
# New interfaces: Acoustic

- Ultrasound imaging module
  - CMUT technology
- Assembly challenges
  - Acoustic matching different materials
  - Stress resistance to exposure to humidity/water/temperature
- Proven assembly technologies
  - Die bonding with adhesive
  - Al wirebonding
- New assembly technologies
  - Window application
  - Lens component placement with adhesive



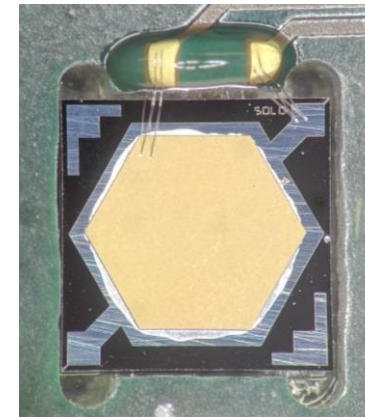
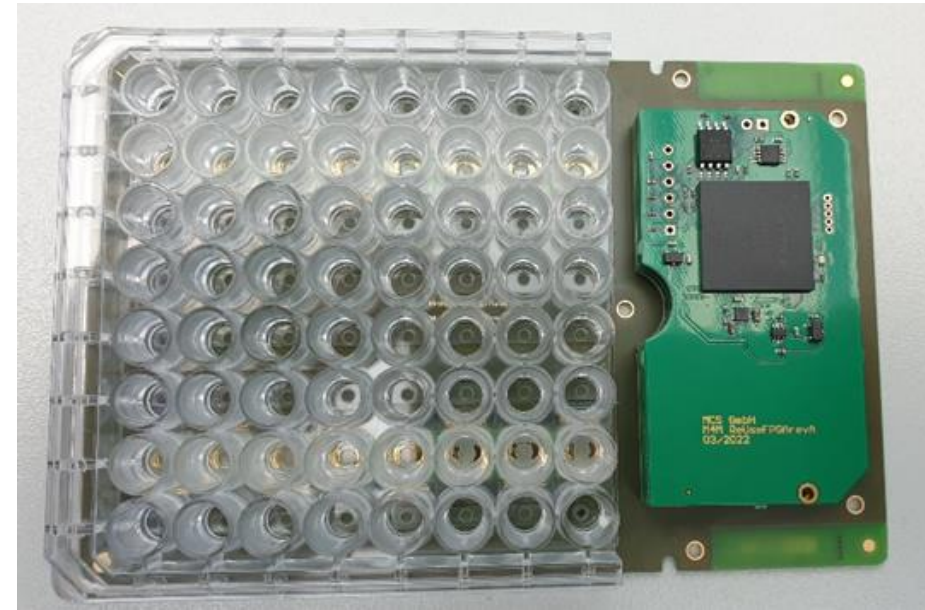
# New interfaces: Optical

- Lidar for landing assistance
  - Optical phase array for beamsteering
  - PIC with fiber input and lens output
- Assembly challenges
  - Submicron alignment lensed fiber (1.5\*0.5micron waveguide)
  - Stable submicron fixation of fiber (<100nm)
  - Lens placement accuracy (odd shape)
- Assembly carrier and concept
  - Developed together with CITC and TNO
  - Cooling design by TNO
  - Electrical assembly by CITC
  - Optical assembly by Philips
- New assembly technologies
  - Active optical alignment fiber to PIC
  - Glue fixation with optimised curing profile
  - Lens component placement with adhesive

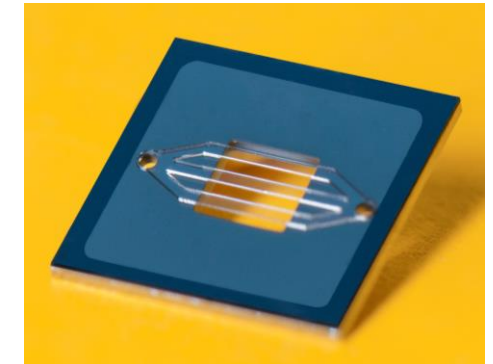


# New interfaces: $\mu$ -fluidic

- Smart Multi-well plate platform
  - Organ on chip dies with electrodes
  - Silicon micro pumps to create a fluidic flow
  - Positions to buffer required fluids (fresh & waste)
  - Electronics to process data acquisition
- Assembly challenges
  - Leak tight assembly
  - Bio-compatible materials and low temperature processes
  - Environmental protection
    - Incubator conditions exposure 4 weeks (40 C / high humidity)
    - Water exposure
- Proven assembly technologies
  - Adhesive die-bonding
  - Wirebonding of dies and micro-pumps
  - Encapsulation of wirebonds (dispense process)
  - Sealing



Si micro pump  
Fraunhofer EMFT



**bi/ond.**

Organ on Chip developed with  
conventional silicon-based  
microfabrication

**Moore4Medical**



H2020-ECSEL-2019-IA-876190  
[www.moore4medical.eu](http://www.moore4medical.eu)

# Conclusions

- The new and exiting development fundamentals
  - Re-use as many as possible proven technologies and standard production equipment
  - Identify new interfaces and requirements
  - De-risk unknowns in a structured Advanced development approach
  - Release new technologies on standard production equipment
- New F2R platform enables next steps in miniaturisation and integration of new functionalities

